2023년 2월 15일(수), 10:45-12:30
Room B (에메랄드 II+III, 5층)

D. Thin Film Process Technology 분과
[WB2-D] Thin Films Transistors II

좌장: 백인환 교수(인하대학교), 안지훈 교수(한양대학교)

WB2-D-1 **10:45-11:15** **[초청]**	**Atomic Layer Deposition for Emerging Semiconducting Materials** In-Hwan Baek[1] and Seong Keun Kim[2,3] *[1]Department of Chemical Engineering, Inha University, [2]Electronic Materials Research Center, KIST, [3]KU-KIST Graduate School of Converging Science and Technology, Korea University*
WB2-D-2 **11:15-11:30**	**Influence of HfO_2-Based Gate Stack on the Performance of P-channel SnO Thin Film Transistor Fabricated by Atomic Layer Deposition** Jina Kim[1], Hee Won Jang[1], Myeong Gil Chae[1], Bo Keun Park[2], Taek-Mo Chung[2], and Jeong Hwan Han[1] *[1]Department of Materials Science and Engineering, Seoul National University of Science and Technology, [2]Division of Advanced Materials, KRICT*
WB2-D-3 **11:30-11:45**	**Two-Dimensional Tin Sulfide Compounds Deposited by Atomic Layer Deposition Using a Novel Tin Precursor** Dong Geun Kim, Jeong-Hun Choi, Ji-Min Lee, and Ji-Hoon Ahn *Department of Materials Science and Chemical Engineering, Hanyang University*
WB2-D-4 **11:45-12:00**	**Performance Enhancement of Transparent p-type Copper Oxide Thin Film Transistors with Alkali Metal Doping** Seokhyeon Baek, Wonsik Kim, Taehyun Kwak, and Sungjun Park *Department of Electrical and Computer Engineering, Ajou University*
WB2-D-5 **12:00-12:15**	**Low-temperature Growth of 2D-MoS_2 Thin Films by Plasma-enhanced Atomic Layer Deposition Using New Molybdenum Precursor** Jeong-Hun Choi, Dong Geun Kim, Min-Ji Ha, Ji-Min Lee, and Ji-Hoon Ahn *Department of Materials Science and Chemical Engineering, Hanyang University*
WB2-D-6 **12:15-12:30**	**ALD Supercycle에 따른 다층 구조 ZnO/SnO_2 박막 트랜지스터의 성능 향상에 대한 연구** 박찬영, 이세형, 박소영, 백동기, 이문석 *부산대학교 전기전자공학과*